



US009382492B1

(12) **United States Patent**  
**Morrow et al.**

(10) **Patent No.:** **US 9,382,492 B1**  
(45) **Date of Patent:** **Jul. 5, 2016**

(54) **LANDFILL GAS TREATMENT METHOD WITH OFFSHOOT**

(71) Applicants: **David C. Morrow**, Midland, TX (US);  
**Paul D. Morrow**, Midland, TX (US);  
**Luke N. Morrow**, Midland, TX (US)

(72) Inventors: **David C. Morrow**, Midland, TX (US);  
**Paul D. Morrow**, Midland, TX (US);  
**Luke N. Morrow**, Midland, TX (US)

(\*) Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 0 days.

3,618,331 A	11/1971	Smith
3,767,766 A	10/1973	Tjoa et al.
4,000,990 A	1/1977	Bingham
4,080,424 A	3/1978	Miller et al.
4,097,250 A	6/1978	Pagani
4,242,108 A	12/1980	Nicholas et al.
4,270,937 A	6/1981	Adler
4,318,723 A	3/1982	Holmes
4,371,381 A	2/1983	Schuftan
4,417,449 A	11/1983	Hegarty et al.
4,449,994 A	5/1984	Hegarty
4,459,142 A	7/1984	Goddin
4,475,347 A	10/1984	Hegarty
4,478,798 A	10/1984	Karwat
4,491,566 A	1/1985	Adams et al.
4,518,399 A	5/1985	Croskell
4,548,620 A	10/1985	Albiol

(21) Appl. No.: **15/135,903**

(Continued)

(22) Filed: **Apr. 22, 2016**

#### OTHER PUBLICATIONS

Sherman; Morphysorb Process Application for Landfill Gas; IGT Analytical Report; Apr. 23, 1999; Des Plaines, IL.

(Continued)

#### Related U.S. Application Data

(60) Division of application No. 14/458,128, filed on Aug. 12, 2014, now Pat. No. 9,340,739, which is a continuation-in-part of application No. 13/199,596, filed on Sep. 2, 2011, now Pat. No. 8,840,708.

#### (51) Int. Cl.

**B01D 53/14** (2006.01)

**C10L 3/10** (2006.01)

**B01D 19/00** (2006.01)

#### (52) U.S. Cl.

CPC ..... **C10L 3/104** (2013.01); **B01D 53/14** (2013.01); **B01D 53/1406** (2013.01); **B01D 53/1425** (2013.01); **B01D 53/1475** (2013.01); **B01D 19/0036** (2013.01)

#### (58) Field of Classification Search

None

See application file for complete search history.

#### (56) References Cited

##### U.S. PATENT DOCUMENTS

2,982,721 A	5/1961	Dow
3,121,624 A	2/1964	Matsch
3,469,934 A	9/1969	Bocard

*Primary Examiner* — Duane Smith

*Assistant Examiner* — Phillip Shao

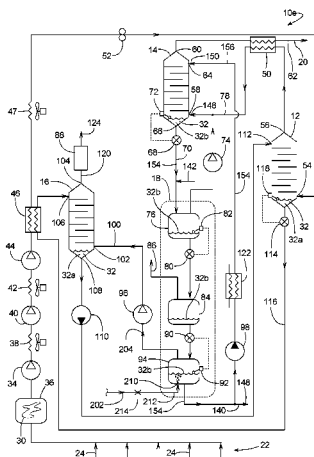
(74) *Attorney, Agent, or Firm* — www.bobharter.com; Robert J. Harter

(57)

#### ABSTRACT

A method for recovering methane gas from a landfill involves the use of a main absorber, a flash system, an optional ancillary absorber and an optional polishing absorber. The recovered gas is maintained at a temperature that enhances a solvent's ability to absorb carbon dioxide from the recovered gas. While the main absorber uses the solvent for absorbing most of the carbon dioxide from the recovered gas, the flash system removes much of the carbon dioxide from the solvent exiting the main absorber. In some examples, at least portion of the flash system operates at subatmospheric pressure to create a vacuum that draws in a generally inert stripper gas (e.g., air, nitrogen, etc.) at atmospheric pressure. The stripper gas helps remove carbon dioxide from the solvent in the flash system.

**1 Claim, 7 Drawing Sheets**



(56)

## References Cited

## U.S. PATENT DOCUMENTS

4,563,202	A	1/1986	Yao
4,575,387	A	3/1986	Larue
4,609,384	A	9/1986	Ranke
4,675,035	A	6/1987	Apffel
4,681,612	A	7/1987	O'Brien
4,720,294	A	1/1988	Lucadamo
4,747,858	A	5/1988	Gottier
4,749,555	A	6/1988	Bush
4,762,543	A	8/1988	Pantermuehl
4,770,676	A	9/1988	Sircar
4,869,894	A	9/1989	Wang
H825	H	10/1990	Green
5,059,405	A	10/1991	Watson
5,198,001	A	3/1993	Knebel
5,335,504	A	8/1994	Durr
5,451,249	A	9/1995	Spiegel
5,453,210	A	9/1995	Bardasz
5,529,612	A	6/1996	Troost
5,642,630	A	7/1997	Abdelmalek
5,664,911	A	9/1997	Bridges
5,681,360	A	10/1997	Siwajek et al.
5,842,357	A	12/1998	Siwajek
5,938,819	A	8/1999	Seery
5,961,701	A	10/1999	Hlynsky
6,071,326	A	6/2000	Hall
6,666,908	B2	12/2003	Cadours et al.
6,929,680	B2	8/2005	Krushnelych et al.
6,945,029	B2	9/2005	Viteri
6,969,562	B2	11/2005	Su et al.
7,699,914	B1	4/2010	Morrow et al.
8,282,899	B2	10/2012	Bahr et al.
8,287,625	B2	10/2012	Casella
8,518,155	B2	8/2013	Palamara et al.
8,696,798	B2	4/2014	Mak
2009/0241778	A1	10/2009	Lechnick et al.

## OTHER PUBLICATIONS

Dinsmore; High BTU Landfill Gas Recovery Using Pressure Swing MDEA Process; Published Paper; Aug. 18, 1998; John Zink Company; Tulsa, OK.

Koch; A New Process for the Production of High BTU Gas; Published Paper; Aug. 18, 1998; Air Products and Chemicals, Inc.; Allentown, PA.

Shah; Selexol Solvent Landfill Gas Treating Unit Process Design Information Package; Process Evaluation Report; Dec. 12, 1996; Process Design Services, Inc.; Akron, OH.

Wheless; Production and Utilization of Landfill Gas Derived CNG in Heavy-Duty Class 8 Trucks; Published Paper; Nov. 1996; TOPTEC; Costa Mesa, CA.

Cosulich; Converting Landfill Gas to Vehicle Fuel; Article; Jan. 1996; Natural Gas Fuels; RP Publishing; Denver, CO.

Wheless; Trash is Your Friend; Article; May 1996; Natural Gas Fuels; RP Publishing; Denver, CO.

Wehless; Converting Landfill Gas to Vehicle Fuel; Article; Jan. 1996; Natural Gas Fuels; RP Publishing; Denver, CO.

Epps; Use of Selexol Solvent for Hydrocarbon Dewpoint Control and Dehydration of Natural Gas; Presentation; Feb. 28, 1994; Norman, OK.

Maguin; Processing and Utilization of Landfill Gas as a Clean Alternative Vehicle Fuel; Paper describing facility installation; Oct. 1993; Whittier CA.

Epps; Processing of Landfill Gas for Commercial Applications; Presentation; Jun. 15, 1992; Union Carbide Chemicals and Plastics Technology Corp., Houston, TX.

Bucklin; Comparison of Fluor Solvent and Selexol Processes; AIChE Symposium; Mar. 11, 1984; AIChE; Atlanta, GA.

Judd; Gas-Process-Plant Conversion Cuts Energy Use, Emissions; Article; Oil and Gas Journal; May 8, 1978; Pennwell Publishing; Tulsa, OK.

Raney; Bulk Removal of Carbon Dioxide with Selexol at Pikes Peak Plant; Paper describing facility installation; Feb. 15, 1974; Dallas, TX.

FIG. 1

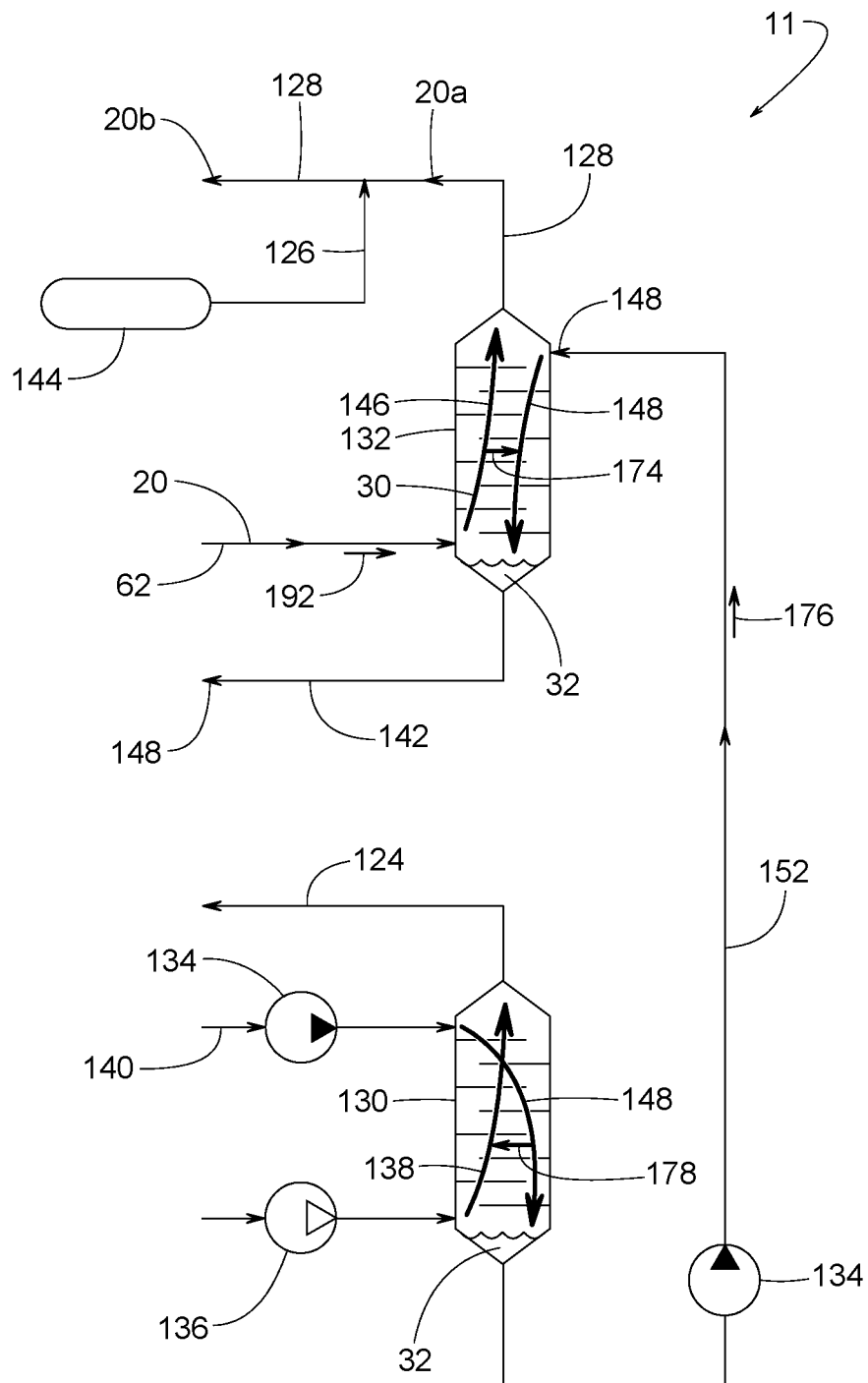


FIG. 2

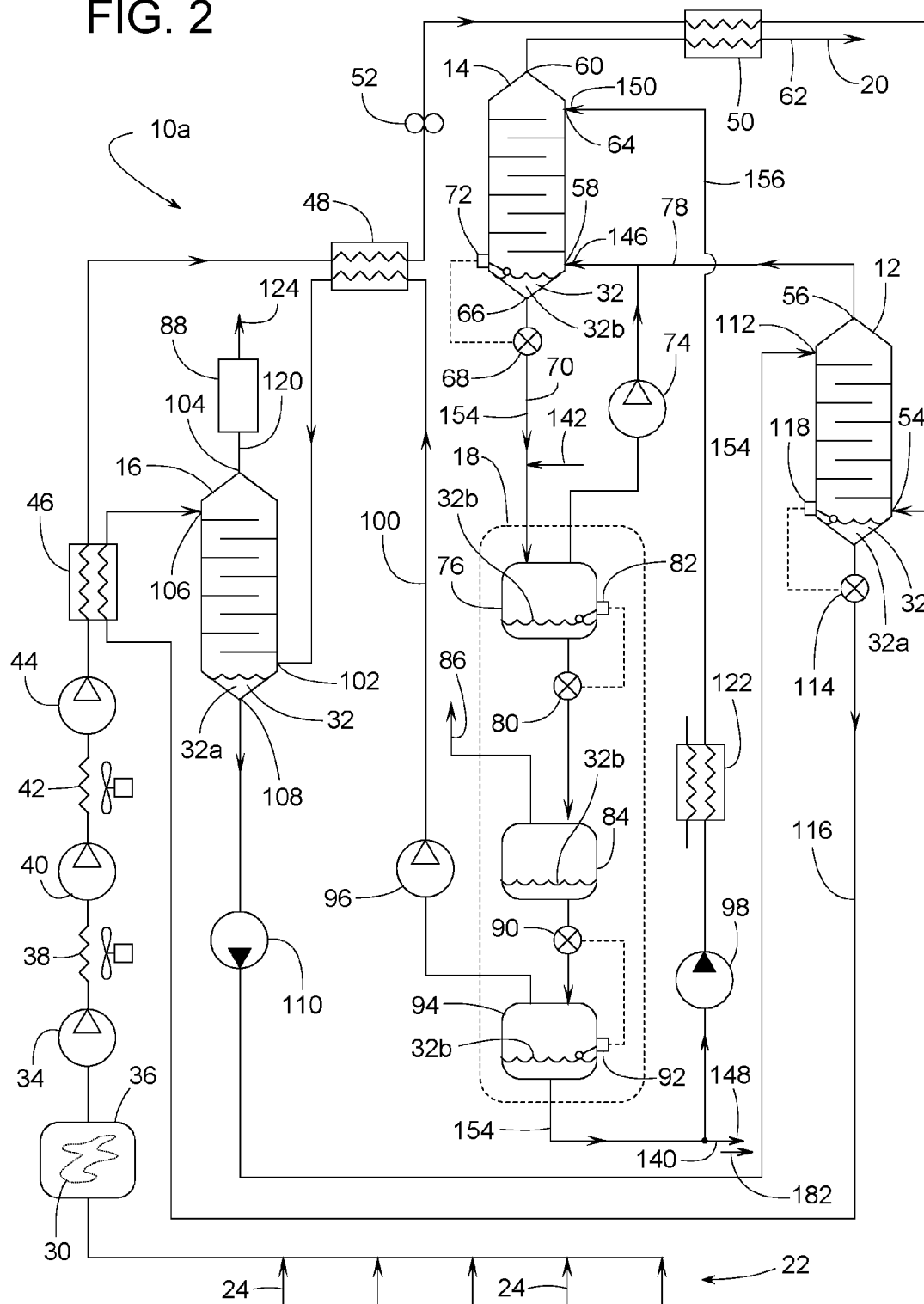


FIG. 3

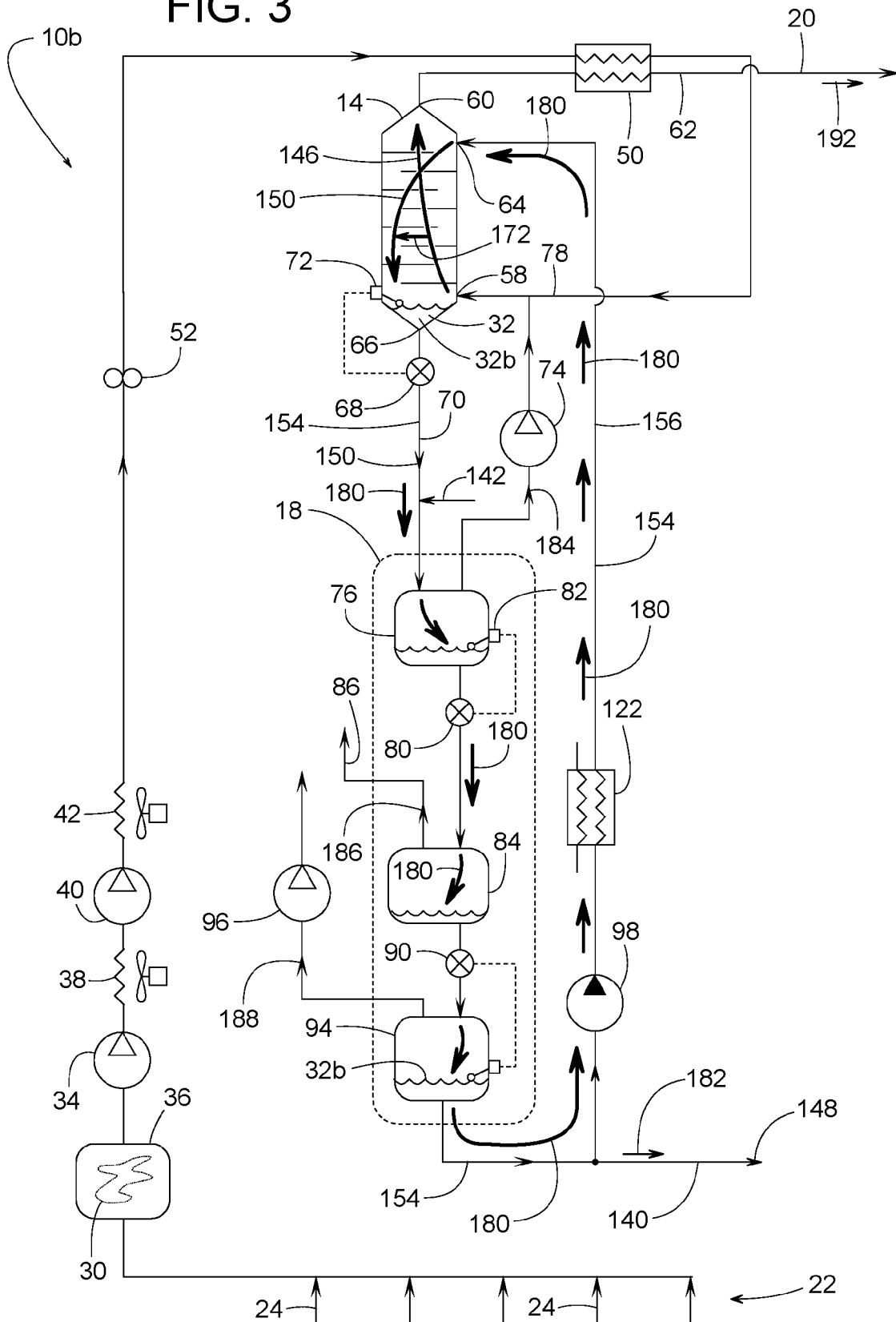


FIG. 4

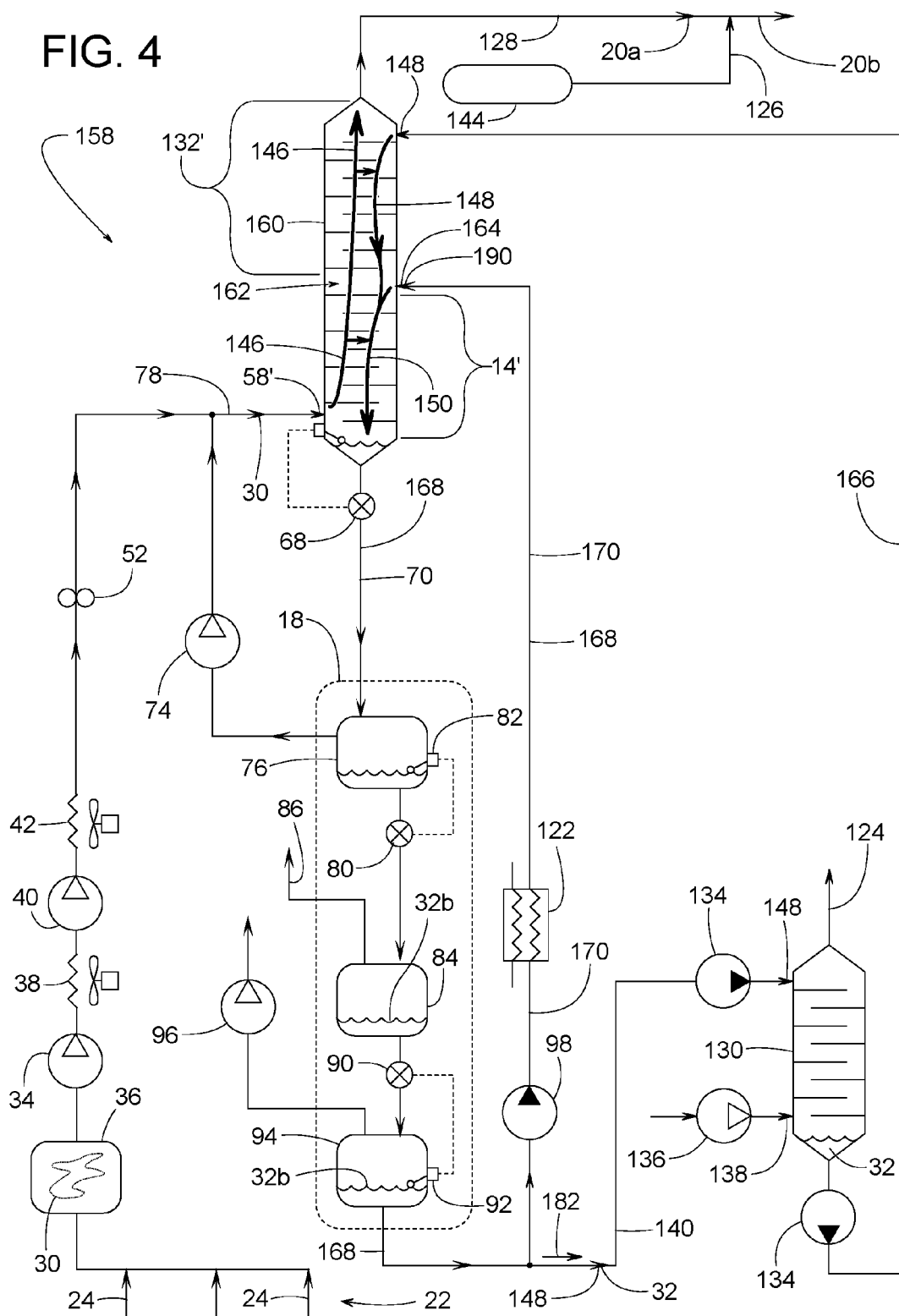


FIG. 5

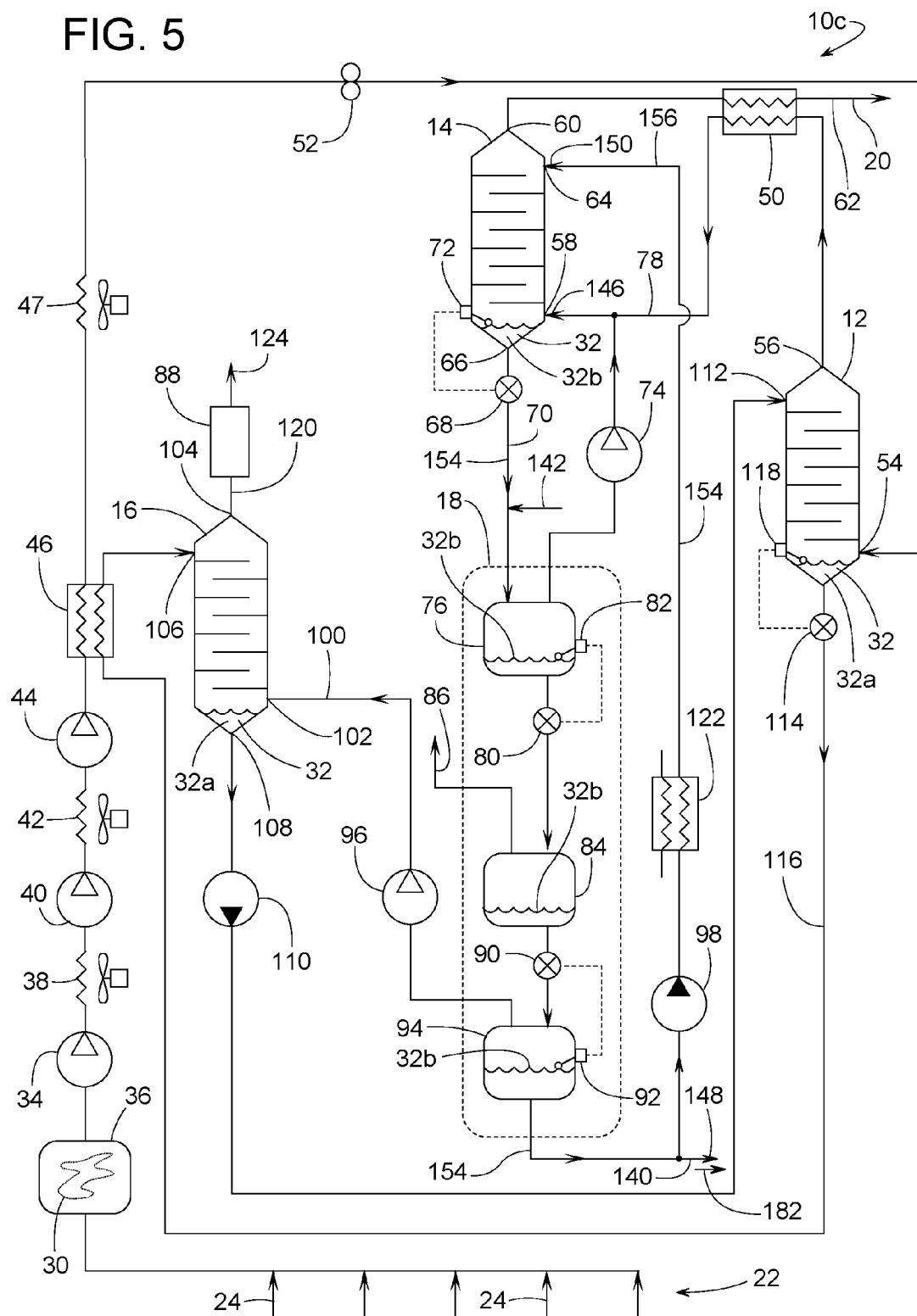


FIG. 6

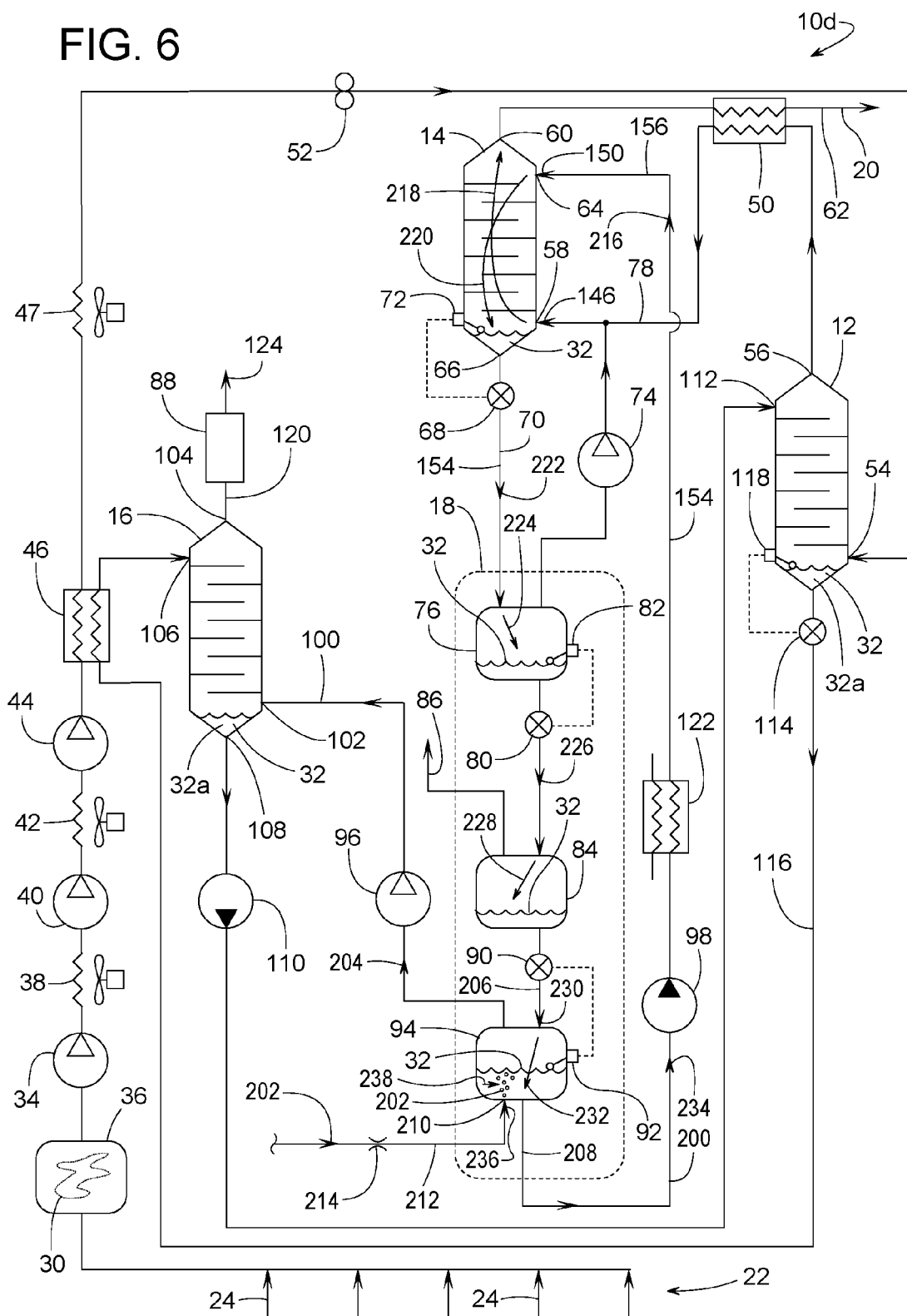
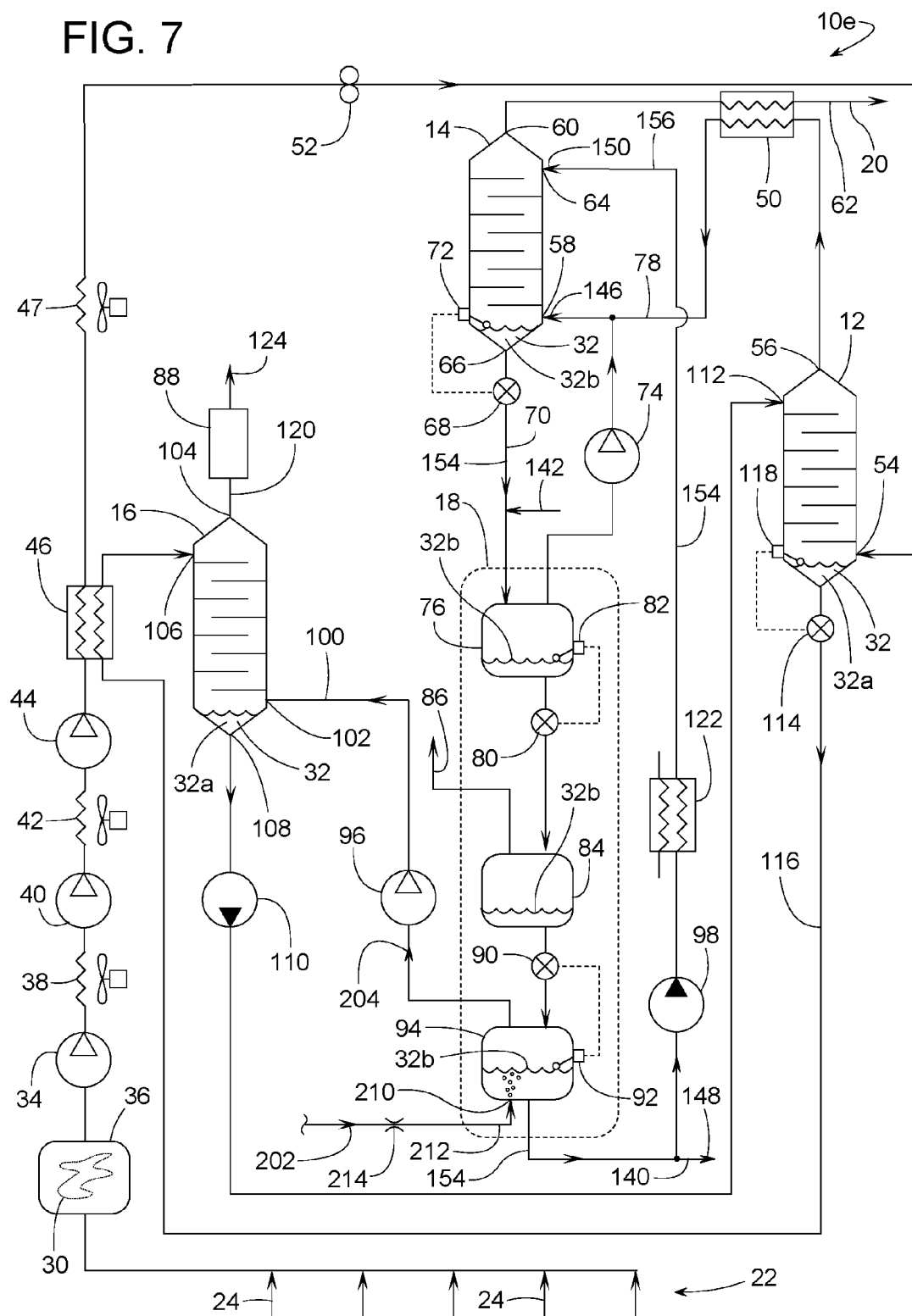




FIG. 7



1

# LANDFILL GAS TREATMENT METHOD WITH OFFSHOOT

## CROSS REFERENCE TO RELATED APPLICATIONS

This application is a division of co-pending patent application Ser. No. 14/458,128 filed on Aug. 12, 2014; which is a continuation-in-part of patent application Ser. No. 13/199,596 filed on Sep. 2, 2011 now U.S. Pat. No. 8,840,708.

## FIELD OF THE DISCLOSURE

The subject invention generally pertains to processing landfill gas and more specifically to an absorption system and method for recovering and purifying methane gas.

## BACKGROUND

Decomposing garbage buried in a landfill can generate landfill gas that can be extracted and processed to provide methane gas of varying degrees of purity and energy content. Processing plants have been developed for recovering and purifying methane gas, but there continues to be a need for better systems and methods.

## BRIEF DESCRIPTION OF THE DRAWINGS

FIG. 1 is a schematic view of an example absorption system and method.

FIG. 2 is a schematic view of an example absorption system connectable to the system shown in FIG. 1.

FIG. 3 is a schematic view of another example absorption system connectable to the system shown in FIG. 1.

FIG. 4 is a schematic view of yet another example absorption system and method.

FIG. 5 is a schematic view of another example absorption system connectable to the system shown in FIG. 1.

FIG. 6 is a schematic view of another example absorption system and method.

FIG. 7 is a schematic view of another example absorption system connectable to the system shown in FIG. 1.

## DETAILED DESCRIPTION

FIG. 1 shows an example absorption system 11 for improving the gas purifying operation of various methane gas processing systems. Examples of such gas processing systems include, but are not limited to, a triple-effect absorption system 10a, shown in FIG. 2, and an absorption system 10b, shown in FIG. 3. To understand the purpose and function of absorption system 11, the structure and operation of systems 10a and 10b will be explained first.

Referring to FIG. 2, triple-effect absorption system 10a includes a first absorber 12, a second absorber 14, a third absorber 16, plus a flash system 18 that work together to recover relatively clean methane gas 20 from a landfill 22. Landfill 22 is a large field of buried garbage with a series of wells 24 that tap a landfill gas 30 generated by the decomposing garbage. Landfill gas 30 may be comprised of methane contaminated with various impurities such as CO<sub>2</sub> (carbon dioxide), air, hydrocarbons, H<sub>2</sub>S (hydrogen sulfide), aromatics and water. Each impurity's concentration may vary from its initial level in the landfill down to zero as gas 30 is progressively processed through system 10a.

To recover and separate the methane from its contaminants, a solvent 32 having an affinity for contaminants is circulated

2

through absorbers 12, 14 and 16. In first absorber 12, solvent 32 absorbs trace contaminants of hydrocarbons, aromatics and water from landfill gas 30. In second absorber 14, solvent 32 absorbs CO<sub>2</sub> from gas 30. And in third absorber 16, CO<sub>2</sub> absorbs trace contaminants from solvent 32. Solvent 32 represents any chemical that can absorb and subsequently release one or more impurities that can contaminate methane gas. Examples of solvent 32 include, but are not limited to, SELEXOL (registered trademark of Union Carbide Chemicals & Plastics Technology Corporation of The Dow Chemical Company) and DEPG (diethylpropylene glycol). System 10a has two charges of solvent 32. A first portion 32a of solvent 32 circulates between absorbers 12 and 16, and a second portion 32b of solvent 32 circulates between absorber 14 and flash system 18.

In operation, a blower 34 draws landfill gas 30 up from within wells 24 into a collection tank 36. Blower 34 operates at an absolute suction pressure of about 10 to 60 inch water vacuum (subatmospheric pressure) and a discharge pressure of about 3 psig. A cooler 38 reduces the temperature of gas 30 from about 160° F. to about 120° F. A screw compressor 40 takes the temperature and pressure of gas 30 to about 230° F. and 85 psig. A cooler 42 reduces the temperature of gas 30 to about 120° F. A reciprocating compressor 44 increases the pressure of gas 30 to about 450 psig. In the example of FIG. 2, a solvent heat exchanger 46, a CO<sub>2</sub> heat exchanger 48, and a methane heat exchanger 50 each extracts heat from compressed gas 30 to enhance the effectiveness of system 10a. In the examples shown in FIGS. 5-7, an air cooler 47 cools the compressed gas 30 to about 120° F. In some examples, a conventional sulfur treater 52 is used to help extract at least some hydrogen sulfide and mercaptan compounds from gas 30.

In the example of FIG. 2, gas 30 enters a lower gas inlet 54 of absorber 12 at about 120° F. and 450 psig, travels upward through absorber 12, and exits through an upper gas outlet 56 of absorber 12 at about 450 psig. As gas 30 travels through first absorber 12, first solvent portion 32a travels downward in intimate contact with gas 30 to absorb trace contaminants from gas 30. With most or at least some of the trace contaminants removed, gas 30 enters a lower gas inlet 58 of second absorber 14 at about 125° F. and 450 psig. Gas 30 leaving absorber 12 is comprised of about 42 mol % CO<sub>2</sub>. It should be noted that the term, "mol %," as used throughout this patent, means molar percent, which is the ratio of the moles of a substance in a mixture to the total moles of the mixture with the ratio being multiplied by a hundred, i.e., mol % represents the number of moles of a substance in a mixture as a percentage of the total number of moles in the mixture. The term, "concentration," as used throughout this patent, is expressed in terms of mol %.

To remove CO<sub>2</sub> from gas 30, the gas travels upward from lower gas inlet 58 to an upper gas outlet 60 to release the CO<sub>2</sub> to second solvent portion 32b, which travels downward in intimate, CO<sub>2</sub>-absorbing contact with gas 30. With most of the CO<sub>2</sub> now removed from gas 30, the gas is conveyed to a supply line 62 where the treated gas 20 is available for further processing. Prior to reaching supply line 62, however, gas 20 leaving second absorber 14 first passes through heat exchanger 50 to precool gas 30 that is about to enter lower gas inlet 54 of first absorber 12.

Second solvent portion 32b, which absorbs CO<sub>2</sub> from gas 30 in second absorber 14, travels downward from an upper liquid inlet 64 to collect just above a lower liquid outlet 66. The second solvent portion 32b is at about 50 to 55° F. A control valve 68 in a solvent line 70 (second solvent line) responds to a liquid level sensor 72 to maintain a predeter-

mined head of liquid solvent **32b** at the bottom of second absorber **14**. Valve **68** controllably releases solvent **32b** at about 450 psig in second absorber **14** to first flash tank **76** at about 250 psig. The lower pressure in first flash tank **76** causes some CO<sub>2</sub> to be released from the second solvent portion **32b**. Compressor **74** returns this CO<sub>2</sub> along with some methane to a gas line **78** to mix with gas **30** from first absorber **12**. Together, gas line **78** and compressor **74** feed second absorber **14** with gas **30** that is about 45 mol % CO<sub>2</sub>.

The second solvent portion **32b** pools at the bottom of first flash tank **76**. A control valve **80** (first control valve) responsive to a liquid level sensor **82** controls the liquid level in first flash tank **76** and controllably feeds second solvent portion **32b** into a second flash tank **84**, which is slightly above atmospheric pressure. The pressure drop from flash tank **76** to flash tank **84** causes more CO<sub>2</sub> to escape from the second solvent portion **32b**. That CO<sub>2</sub> is surplus, as it is not needed for stripping trace contaminants from the first solvent portion **32a** in third absorber **16**, thus that portion of the CO<sub>2</sub> can be vented directly, or through a carbon filter, to atmosphere via a vent line **86**. If that CO<sub>2</sub> were not vented to atmosphere but instead directed into third absorber **16**, the surplus CO<sub>2</sub> would create an unnecessary incineration load on an incinerator **88**, which will be explained later.

Another control valve **90** (second control valve) responsive to a liquid level sensor **92** in a downstream third flash vessel **94** controls the liquid level in third flash tank **94** and controllably feeds the second solvent portion **32b** into third flash tank **94**. A compressor **96** maintains third flash tank **94** at about a 4 to 5 psia (negative gage pressure of about -9 to -10 psig), which cause additional CO<sub>2</sub> to escape from the second solvent portion **32b**. This additional CO<sub>2</sub> is later used in third absorber **16** to remove the trace contaminants from first solvent portion **32a**. A pump **98** draws the liquid second portion **32b** of solvent **32** from the bottom of flash tank **94** and returns it to upper liquid inlet **60** of second absorber **14** to drive the solvent cycle of second absorber **14** and flash system **18**.

To strip the trace contaminants from the first portion **32a** of solvent **32**, compressor **96** draws CO<sub>2</sub> from third flash tank **94**, and a CO<sub>2</sub> line **100** and heat exchanger **48** convey the CO<sub>2</sub> into a lower gas inlet **102** of third absorber **16**. Vent line **86** represent a first flow path, and CO<sub>2</sub> line **100** represents a second flow path for the CO<sub>2</sub>. With two flow paths, only a minimal amount of CO<sub>2</sub> is used for stripping trace contaminants from first portion **32a** of solvent **32** in third absorber **16**, and surplus CO<sub>2</sub> can be vented directly to atmosphere.

In some examples, as shown in FIG. 2, heat exchanger **48** heats the CO<sub>2</sub> before the CO<sub>2</sub> enters third absorber **16**. Once inside third absorber **16**, the CO<sub>2</sub> travels upward to an upper gas outlet **104**. At the same time, the first solvent portion **32a** with absorbed trace contaminants travels from an upper liquid inlet **106** in third absorber **16** down to a lower liquid outlet **108**. As this first solvent portion **32a** and the CO<sub>2</sub> travel in intimate contact with each other inside third absorber **16**, the CO<sub>2</sub> strips contaminants from the first solvent portion **32a**.

The resulting relatively uncontaminated first solvent portion **32a** collects at the bottom of third absorber **16**. A pump **110** returns the clean first solvent portion **32a** to an upper gas inlet **112** of absorber **12** so that the first solvent portion **32a** can absorb additional trace contaminants from the incoming landfill gas **30**.

To maintain first solvent portion **32a** at a certain liquid level at the bottom of first absorber **12**, a control valve **114** in a first solvent line **116** responds to a liquid level sensor **118**, thereby controlling the delivery of first solvent portion **32a** to third absorber **16** and maintaining a predetermined pressure differential between absorbers **12** and **16**. The pressure differential

is about 450 psig and it is that pressure that forces first solvent portion **32a** to upper liquid inlet **106** of third absorber **16**.

Before entering third absorber **16**, first solvent portion **32a** is heated by gas **30** within heat exchanger **46**. Heating first solvent portion **32a** enables the CO<sub>2</sub> in third absorber **16** to more readily strip the trace contaminants from the first solvent portion **32a**, thus less CO<sub>2</sub> is needed for absorbing the contaminants.

After absorbing the trace contaminants from first solvent portion **32a**, the CO<sub>2</sub> and trace contaminants exhaust out through an upper gas outlet **120** of third absorber **16** and enter incinerator **88**. Using the trace contaminants and treated gas **20** as fuel, incinerator **88** heats the CO<sub>2</sub> (from CO<sub>2</sub> line **100**) to at least 1400° F. before exhausting the CO<sub>2</sub> and the resulting combustion products to atmosphere **124**. By venting a portion of the CO<sub>2</sub> through vent line **86**, as opposed to directing all of the CO<sub>2</sub> into third absorber **16**, less energy is needed to heat the contaminated CO<sub>2</sub> to 1400° F., thus the trace contaminants can provide all or at least most of the necessary combustion energy.

To effectively strip CO<sub>2</sub> from the second solvent portion **32b** and supply third absorber **16** with a sufficient amount of CO<sub>2</sub> to thoroughly strip the first solvent portion **32a** of its absorbed trace contaminants yet limit the amount of CO<sub>2</sub> delivered to third absorber **16** so as not to extinguish or dampen the combustion within incinerator **88**, the relative fluid flow rates, temperatures and pressures of system **10a** need to be properly balanced. In some examples, the pressure in first absorber **12** is nearly equal to or at least within 10% of the pressure in second absorber **14**, the pressure in first absorber **12** and second absorber **14** are much greater than and preferably over five times as great as the pressure in third absorber **16**, the flow rate of solvent **32** in first absorber **12** and third absorber **16** are substantially equal or at least within 10% of each other, the flow rate of solvent **32** through second absorber **14** is much greater than and preferably at least ten times as great as the flow rate of solvent through first absorber **12**, and the flow rate of solvent **32** through second absorber **14** is much greater than and preferably at least ten times as great as the flow rate of solvent through third absorber **16**. In some cases, the first solvent portion **32a** flows at about 10 gpm, and the second solvent portion **32b** flows at about 210 gpm.

The pressure inside first absorber **12** is approximately 450 psig, thus the pressure of gas **30** inside first absorber **12** and the pressure of solvent **30** inside first absorber **12** are also at about 450 psig. The pressure inside second absorber **14** is approximately 450 psig, thus the pressure of gas **30** inside second absorber **14** and the pressure of solvent **30** inside second absorber **14** are also at about 450 psig. The pressure inside third absorber **16** is near zero psig, thus the pressure of gas **30** inside third absorber **16** and the pressure of solvent **30** inside third absorber **16** are also at about zero psig.

In some examples, a refrigerated or otherwise cooled heat exchanger **122** is added to cool the second solvent portion **32b** circulated through second absorber **14**. Such cooling increases the second portion's ability to absorb CO<sub>2</sub> inside second absorber **14**. In some examples, the second solvent portion **32b** entering second absorber **14** is naturally cooled to a temperature of about 40 to 50° F. As for the other heat exchangers of system **10a**, the heat supplied to heat exchangers **46**, **48** and **50** would otherwise be wasted heat created directly or indirectly by compressors **34**, **40** and/or **44**. It should be noted that any one or more of heat exchangers **38**, **42**, **46**, **48**, **50**, and **122** may be optionally omitted.

In the example shown in FIG. 3, absorption system **10b** is created by eliminating several components of system **10a**. The eliminated items include absorbers **12** and **14** and their

5

associated components (e.g., items 46, 48, 88, 110, 114, 116 and 118. Remaining portions of absorption system 10b, shown in FIG. 2, are retained to operate in a manner similar to that of system 10a, wherein supply line 62 makes treated gas 20 available for further processing.

Absorption system 11, of FIG. 1, can be added to systems 10a and 10b to improve the quality of methane gas 20. In some examples, gas 20 has a concentration of carbon dioxide of about 2 mol % (or slightly less or more), and system 11 can improve that to provide methane gas 20a with a carbon dioxide concentration of less than 1 mol % and perhaps as low as 0.4 to 0.8 mol %. In some examples, system 11 further improves the quality of gas 20a by injecting a gas with a higher energy content than that of methane. In some cases, for example, propane gas 126 with an energy content of about 2,500 BTU/scf is injected into a discharge line 128 to mix with methane gas 20a. While pure methane has an energy content of about 1,010 BTU/scf, methane gas 20a might have an energy content of less than 950 BTU/scf due to gas 20a having various contaminants, such as nitrogen and some carbon dioxide. Thus, system 11 minimizing the concentration of carbon dioxide in gas 20a and, in some examples, adding propane 126 provides high quality methane 20b having significantly less than 2 mol % of carbon dioxide and an energy content greater than 950 BTU/scf and in some cases greater than 970 BTU/scf.

In the example shown in FIG. 1, system 11 comprises an ancillary absorber 130, a polishing absorber 132, one or more pumps 134 pumping a portion 148 of solvent 32 (portion of solvent 148) through absorbers 130 and 132, an air supply 136 (or supply of nitrogen) forcing a current of air 138 (or current of nitrogen) through ancillary absorber 130, a line 140 conveying the portion of solvent 148 from one absorption system (e.g., system 10a or 10b) to system 11, a return line 142 for injecting the portion of solvent 148 back into the main absorption system (e.g., system 10a or 10b), and discharge line 128 for conveying gas 20a from polishing absorber 132. Examples of supply 136 include, but are not limited to, a blower, a fan, a compressor, a pressurized tank of nitrogen, etc. In some examples, ancillary absorber 130 and/or 132 includes or is associated with means for controlling the flow of solvent through absorber 130 and/or 132. Examples of such means include, but are not limited to, controlling the operation of one or more pumps 134 and/or the use of various flow control elements such as those used in system 10a of FIG. 2 (e.g., control valves 68, 80, 90, 114; and liquid level sensors 72, 82, 92 and 118). Item 144 schematically represents an optional source of propane 126, which normally requires a pump, for injection into gas 20a to produce gas 20b, wherein gas 20b has a higher energy content than that of gas 20a.

In some examples illustrated in FIG. 1, nitrogen is used instead of air, where in such examples, reference numeral 136 refers to a supply of nitrogen and numeral 138 refers to a current of nitrogen. The term "nitrogen" refers to a gas having an appreciably greater concentration of nitrogen than that of just air, e.g., such gas has a nitrogen concentration in excess of 80%. The term, "air" refers to the Earth's atmosphere that when dry is a mixture of approximately 78% nitrogen, 21% oxygen and 1% other gases (percentage values being with respect to volume). The term, "mostly air" refers to a gas mixture wherein at least half of its volume is comprised of 78% nitrogen, 21% oxygen and 1% other gases.

Connecting system 11 of FIG. 1 to system 10a of FIG. 2 or system 10b of FIG. 3 provides a combined absorption system comprising a main absorber (e.g., absorber 14), ancillary absorber 130, polishing absorber 132, flash system 18, and

6

lines 140 and 142 connecting system 11 to system 10a or 10b. In the operation of combined systems 11 and 10a or 11 and 10b, a current of gas 146 (comprising gas 30) flows up through main absorber 14 from inlet 58 to outlet 60. From outlet 60, the current of gas 146 flows sequentially through line 62 to polishing absorber 132, up through polishing absorber 132, and out through discharge line 128 to be used or sold.

To remove carbon dioxide from gas 30, a main current of solvent 150 (comprising solvent 32) flows through main absorber 14 while in intimate contact with the current of gas 146. After the main current of solvent 150 absorbs carbon dioxide from current of gas 146, the main current of solvent 150 flows through flash system 18, which removes carbon dioxide from the main current of solvent 150. While pump 98 pumps most of the current of solvent 150 from the bottom of flash system 18 to inlet 64 of main absorber 14, pump 134 pumps a lesser portion of solvent 148 through line 140 to ancillary absorber 130 (FIG. 1). The portion of solvent 148 flows through ancillary absorber 130 in intimate contact with the current of air 138.

As the current of air 138 and the portion of solvent 148 flow through ancillary absorber 130, the current of air 138 extracts carbon dioxide from the portion of solvent 148. After air 138 removes carbon dioxide from the portion of solvent 148, air 138 is vented to atmosphere via a line 124, and a line 152 conveys the portion of solvent 148 to polishing absorber 132. As the portion of solvent 148 flows through polishing absorber 132, the current of gas 146 from line 62 flows up through polishing absorber 132 in intimate contact with the portion of solvent 148, whereby the portion of solvent 148 absorbs carbon dioxide from the current of gas 146. The current of gas 146 now becomes gas 20a and, in some examples, ultimately becomes gas 20b in cases where propane 126 is added to gas 20a. Gas 20a or 20b can be sold or used as needed.

As for the portion of solvent 148 after having flowed through polishing absorber 132, line 142 injects the portion of solvent 148 back into a main solvent loop 154, wherein main solvent loop 154 comprises main absorber 14, line 70, flash system 18, and a return line 156. In some examples, line 142 injects the portion of solvent 148 at a point between main absorber 14 and flash system 18 (e.g., at or downstream of absorber 14 and at or upstream of flash system 18 with respect to solvent flow). Once injected in main solvent loop 154, in some examples, the portion of solvent 148 becomes part of the main current of solvent 150.

In some examples, as shown in FIG. 4, an absorption system 158 includes the combination of a main absorber 14' and a polishing absorber 132' that share a common outer shell 160 (i.e., absorbers 14' and 132' are combined in a single vessel). In this example, line 78 conveys gas 30 to an inlet 58' of main absorber 14'. From inlet 58', a current of gas 146 flows up through main absorber 14', through an area of transition 162 between main absorber 14' and polishing absorber 132', through polishing absorber 132', and out through discharge line 128.

To remove carbon dioxide from gas 146, a main current of solvent 150 flows through main absorber 14' while being in intimate contact with the current of gas 146. After the main current of solvent 150 absorbs carbon dioxide from the current of gas 146, the main current of solvent 150 flows through flash system 18, which removes carbon dioxide from the main current of solvent 150. Pump 98 pumps most of the main current of solvent 150 from the bottom of flash system 18 to an inlet 164 at the area of transition 162 between absorbers 14' and 132'. At least one pump 134 pumps a lesser portion of

solvent **148** through line **140** to ancillary absorber **130**. The portion of solvent **148** flows through ancillary absorber **130** in intimate contact with the current of air **138**, basically in the manner as shown in FIG. 1.

As the current of air **138** and the portion of solvent **148** flow through ancillary absorber **130**, the current of air **138** extracts carbon dioxide from the portion of solvent **148**. After air **138** removes carbon dioxide from the portion of solvent **148**, air **138** is vented to atmosphere via line **124**, and a line **166** conveys the portion of solvent **148** to polishing absorber **132'**. As the portion of solvent **148** flows downward through polishing absorber **132'**, the current of gas **146** from within main absorber **14'** flows up through polishing absorber **132'** in intimate contact with the portion of solvent **148**, whereby the portion of solvent **148** absorbs carbon dioxide from the current of gas **146**. The current of gas **146** now becomes gas **20a** and, in some examples, ultimately becomes gas **20b** in cases where propane **126** is added to gas **20a**. Gas **20a** or **20b** can be sold or used as needed.

The portion of solvent **148** after having flowed down through polishing absorber **132'**, the portion of solvent **148** passes through area of transition **162** to mix with and become part of main current of solvent **150**, wherein the main current of solvent **150**, including portion **148**, flows down through main absorber **14'**. In this example, system **158** includes a main solvent loop **168** comprising main absorber **14'**, line **70**, flash system **18**, and a return line **170**.

As for various methods pertaining to the examples illustrated in FIGS. 1-4, arrow **146** in FIG. 3 provides at least one example of conveying gas through a main absorber. Arrow **146** of FIGS. 1 and 3 provides at least one example of conveying substantially all of the gas from the main absorber through a polishing absorber. Arrow **150** of FIG. 3 provides at least one example of conveying at a main mass flow rate a main current of solvent through the main absorber, thereby exposing the gas to the main current of solvent. An arrow **172** of FIG. 3 provides at least one example of the main current of solvent extracting carbon dioxide from the gas. Arrow **148** of FIG. 1 provides at least one example of conveying at a polishing mass flow rate a polishing current of solvent through the polishing absorber, thereby exposing the gas to the polishing current of solvent. An arrow **174** of FIG. 1 provides at least one example of the polishing current of solvent extracting additional carbon dioxide from the gas. It has been discovered that, in some examples, it appears that having the solvent's main mass flow rate through the main absorber be at least three times greater than the solvent's polishing mass flow rate in the polishing absorber provides surprisingly good results. In some examples, as shown in FIG. 4, the solvent's mass flow rate pertaining to arrow **150** is at least three times greater than the solvent's mass flow rate pertaining to arrow **148**. In some examples, as shown in FIGS. 1 and 3, the solvent's mass flow rate pertaining to arrow **150** (FIG. 3) is at least three times greater than the solvent's mass flow rate pertaining to arrow **148** (FIG. 1). FIG. 4 showing absorbers **14'** and **132'** as a single vessel provides at least one example illustrating housing the main absorber and the polishing absorber within a common outer shell. Transition area **162** between absorbers **14'** and **132'** provides at least one example illustrating the main absorber and the polishing absorber defining an area of transition therebetween. In FIG. 4, the merging of arrows **148** and **150** provides at least one example illustrating the polishing current of solvent joining and becoming part of the main current of solvent at the area of transition. In FIG. 1, arrow **148** provides at least one example illustrating conveying an ancillary current of solvent through an ancillary absorber. In FIG. 1, an arrow **176** provides at least

one example illustrating the ancillary current of solvent flowing from the ancillary absorber to the polishing absorber. In FIG. 1, arrows **148** and **176** provides at least one example illustrating the ancillary current of solvent flowing from the ancillary absorber becoming the polishing current of solvent flowing through the polishing absorber. In FIG. 1, arrow **138** with reference to arrow **148** provides at least one example illustrating conveying a current of air (or nitrogen) through the ancillary absorber, thereby exposing the ancillary current of solvent to the current of air (or nitrogen). An arrow **178** of FIG. 1 provides at least one example illustrating the current of air (or nitrogen) extracting carbon dioxide from the ancillary current of solvent flowing through the ancillary absorber. Arrow **126** of FIG. 1 provides at least one example illustrating adding propane to the gas after the polishing current of solvent extracts additional carbon dioxide from the gas, wherein arrow **174** provides at least one example illustrating extracting additional carbon dioxide from the gas.

In FIG. 3, arrow **180** provide at least one example illustrating circulating a main current of solvent through a main solvent loop. Arrows **146** and **150** of FIG. 3 provides at least one example illustrating exposing the gas to the main current of solvent, thereby reducing the concentration of carbon dioxide in the gas, wherein arrow **172** provides at least one example illustrating reducing the concentration of carbon dioxide in the gas. Arrow **182**, shown in FIGS. 2-4, provides at least one example illustrating diverting a portion of solvent from the main solvent loop. Arrows **146**, **148** and **174** of FIG. 1 provide at least one example illustrating exposing the gas to the portion of solvent, thereby further reducing the concentration of carbon dioxide in the gas. Arrows **184**, **186** and/or **188** of FIG. 3 provide at least one example illustrating decreasing the concentration of carbon dioxide in the main current of solvent to a lower level (e.g., to about 3 mol % carbon dioxide at a point between flash vessel **94** and pump **98**), wherein arrows **184**, **186** and **188** represent carbon dioxide leaving the main current of solvent. Arrow **178** of FIG. 1 provides at least one example illustrating decreasing the concentration of carbon dioxide in the portion of solvent to less than the lower level (e.g., to about 0.5 mole % carbon dioxide or even less than that, which in either case, is less than 3 mol % carbon dioxide). Arrow **174** of FIG. 1 provides at least one example illustrating increasing the concentration of carbon dioxide in the portion of solvent to an upper level (e.g., 0.6 to 5 mol % carbon dioxide). Arrow **172** of FIG. 3 provides at least one example illustrating increasing the concentration of carbon dioxide in the main current of solvent to greater than the upper level (e.g., to 35 mol % carbon dioxide). Arrows **150** and **180** of FIG. 3 provide at least one example illustrating the main solvent loop passing through the main absorber and the flash system. Arrows **176** and **148** of FIG. 1 provide at least one example illustrating the portion of solvent flowing through the ancillary absorber and the polishing absorber. Arrows **150**, **146** and **172** of FIG. 3 provide at least one example illustrating exposing the gas to the main current of solvent and reducing the concentration of carbon dioxide in the gas flowing through the main absorber. Arrows **146**, **148** and **174** of FIG. 1 provide at least one example illustrating exposing the gas to the portion of solvent and further reducing the concentration of carbon dioxide in the gas flowing through the polishing absorber. Arrow **188** of FIG. 3 provides at least one example illustrating decreasing the concentration of carbon dioxide in the main current of solvent to the lower level and doing so within the flash system. Arrow **178** of FIG. 1 provides at least one example illustrating decreasing the concentration of carbon dioxide in the portion of solvent to less than the lower level and doing so within the ancillary

absorber. Arrow 174 of FIG. 1 provides at least one example illustrating increasing the concentration of carbon dioxide in the portion of solvent to the upper level and doing so within the polishing absorber. Arrow 172 of FIG. 3 provides at least one example illustrating increasing the concentration of carbon dioxide in the main current of solvent to greater than the upper level and doing so within the main absorber. Arrow 142 of FIG. 3 provides at least one example illustrating that after diverting the portion of solvent from the main solvent loop (arrow 182 illustrates diverting the portion), injecting the portion of solvent back into the main solvent loop at a point between the main absorber and the flash system. An arrow 190 of FIG. 4 provides at least one example illustrating that after diverting the portion of solvent from the main solvent loop (e.g., arrow 182 illustrates diverting the portion), injecting the portion of solvent back into the main solvent loop at a point (e.g., transition area 162) between the polishing absorber (e.g., absorber 132') and the main absorber (e.g., absorber 14'). Arrow 142 of FIG. 3 illustrates that after diverting the portion of solvent from the main solvent loop (e.g., arrow 182 illustrates diverting the portion), injecting the portion of solvent back into the main solvent loop at a point (e.g., such injecting being illustrated by arrow 142 of FIG. 3) where the portion of solvent has a concentration of carbon dioxide that is closer to the upper level (e.g., 2 to 6 mol % carbon dioxide) than to the lower level (e.g., 1 to 3.5 mol % carbon dioxide). Arrows 138, 148 and 178 of FIG. 1 provide at least one example of decreasing the concentration of carbon dioxide in the portion of solvent to less than the lower level and doing so by conveying a current of air in intimate contact with the portion of solvent.

Arrows 148 and 182 and line 140 of FIGS. 1 and 3 provide at least one example illustrating diverting (arrow 182) a portion of solvent from the main solvent loop to create an offshoot solvent path (line 140) conveying an ancillary current of solvent (arrow 148) and a polishing current of solvent (arrow 148), the ancillary current of solvent flowing through an ancillary absorber, the polishing current of solvent flowing through a polishing absorber. Arrow 192 and line 62 of FIGS. 1 and 3 provide at least one example illustrating a pipe conveying the gas from the main shell to the polishing shell. Arrow 142 of FIG. 3 provides at least one example illustrating injecting the portion of solvent back into the main solvent loop at a point downstream of the main absorber and upstream of the flash system.

FIGS. 5, 6 and 7 illustrate example absorption systems 10c, 10d and 10e, respectively, wherein at least portions of absorption systems 10c, 10d and 10e can be used in addition or as an alternative to the examples illustrated in FIGS. 1-3. System 10c of FIG. 5 is similar to system 10a of FIG. 2 with a few exceptions. Instead of conveying recovered gas 30 from heat exchanger 46 through heat exchanger 48 (FIG. 2), recovered gas 30 flows from heat exchanger 46, through a cooler 47 and onto sulfur treater 52. From sulfur treater 52, recovered gas 30 bypasses heat exchanger 50 and flows directly to lower gas inlet 54 of absorber 12. This ensures that recovered gas 30 entering absorber 12 will be at a higher temperature to retard the recovered gas's release of CO<sub>2</sub> as gas 30 flows through absorber 12. With the elimination of heat exchanger 48 (FIG. 2), compressor 96 forces the CO<sub>2</sub> drawn from flash tank 94 directly into lower gas inlet 102 of third absorber 16, as shown in FIG. 5.

In the examples shown in FIGS. 5-7, gas 30 enters a lower gas inlet 54 of absorber 12 at about 120° F. and 450 psig, travels upward through absorber 12, and exits through an upper gas outlet 56 of absorber 12 at about 450 psig. As gas 30 travels through first absorber 12, first solvent portion 32a

travels downward in intimate contact with gas 30 to absorb trace contaminants from gas 30. With most or at least some of the trace contaminants removed, gas 30 enters feed gas to pipeline gas heat exchanger 50 to the lower gas inlet 58 of second absorber 14 at about 75° F. and 450 psig. Also, prior to reaching supply line 62, gas 20 leaving second absorber 14 first passes through heat exchanger 50 to precool gas 30 (flowing to line 78) that is about to enter lower gas inlet 58 of second absorber 14. Precooling gas 30 prior to it entering second absorber 14 promotes the absorption of CO<sub>2</sub> from the high CO<sub>2</sub> gas stream.

Another difference between system 10c of FIG. 5 and system 10a of FIG. 2 pertains to the use of heat exchanger 50. Heat exchanger 50 when connected as shown in FIG. 5 transfers heat from gas 30 flowing from upper gas outlet 56 to lower gas inlet 58 to gas 30 flowing from sulfur treater 52 to supply line 62.

System 10d of FIG. 6 is similar to system 10c of FIG. 5 but with a few changes. With system 10d, instead of line 140 (FIG. 5) diverting a portion of solvent 148 to ancillary absorber 130 and polishing absorber 132 (FIG. 1) and line 142 returning solvent portion 148 back into the main absorption system, a line 200 conveys solvent 32 directly from flash tank 94 to pump 98. In the example shown in FIG. 6, absorbers 130 and 132 are eliminated. To compensate for the loss of absorbers 130 and 132, a source of stripper gas 202 is injected into third flash tank 94. Examples of stripper gas 202 include, but are not limited to, air, nitrogen, an inert gas, and various mixtures thereof. In some examples, the inert gas for stripping is produced by burning natural gas in air, thereby creating an inert mixture of approximately 79% nitrogen and 21% CO<sub>2</sub> (by volume). Stripper gas 202 strips CO<sub>2</sub> from solvent 32 in flash tank 94. Stripper gas 202 stripping and collecting CO<sub>2</sub> and/or other impurities from solvent 32 within flash tank 94 creates an impure stripper gas 204, which compressor 96 sucks from flash tank 94 and delivers to line 100 leading to lower gas inlet 102 of third absorber 16.

With flash tank 94 being at subatmospheric pressure due to compressor 96 (vacuum pump) and with stripper gas 202, in some examples, being at atmospheric pressure, such a differential between atmospheric and subatmospheric pressure is in itself sufficient for injecting stripper gas 202 into flash tank 94. In some examples, a line 212 conveying stripper gas 202 to flash tank 94 has some flow resistance 214 so that stripper gas 202 can enter line 212 at atmospheric pressure while flash tank 94 can be a subatmospheric pressure. Flow resistance 214 is schematically illustrated to represent any means for resisting flow. Examples of flow resistance 214 include, but are not limited to, line 212 being of a limited diameter, an orifice, a valve, a screen, etc.

Stripper gas 202 can be injected into third flash tank 94 at any injection point (e.g., injection point 210) between a flash tank inlet 206 and a flash tank outlet 208 of flash tank 94. To maximize surface contact and/or mixing between stripper gas 202 and solvent 32, the stripper gas injection point, in some examples, is below the liquid level of solvent 32 in flash tank 94 so that stripper gas 202 bubbles up through a pool of liquid solvent 32. In some examples, to further maximize surface contact and/or promote mixing of stripper gas 202 and solvent 32, flash tank 94 includes mixing baffles, a serpentine flow pattern, a mechanical mixer, a flow distributor and/or some other mixing means.

FIG. 6 also illustrates a method for using solvent 32 in treating recovered gas 30 from landfill 22, wherein gas 30 and solvent 32 have a varying concentration of carbon dioxide. In the method illustrated in FIG. 6, arrow 216 represents conveying the main current of solvent 32 to main absorber 14 that

11

defines upper liquid inlet **64**, lower liquid outlet **66**, lower gas inlet **58** and upper gas outlet **60**. Arrow **218** represents conveying recovered gas **30** through main absorber **14** from lower gas inlet **58** to upper gas outlet **60**. Arrow **220** represents conveying the main current of solvent **32** through main absorber **14** from upper liquid inlet **64** to lower liquid outlet **66**. Arrow **222** represents conveying the main current of solvent **32** from lower liquid outlet **66** to first flash tank **76**. Arrow **224** represents conveying the main current of solvent **32** through first flash tank **76**. Arrow **226** represents conveying the main current of solvent **32** from first flash tank **76** to second flash tank **84**. Arrow **228** represents conveying the main current of solvent **32** through second flash tank **84**. Arrow **230** represents conveying the main current of solvent **32** from second flash tank **84** to third flash tank **94**. Arrow **232** represents conveying the main current of solvent **32** through third flash tank **94** from flash tank inlet **206** to flash tank outlet **208** of third flash tank **94**. Arrow **234** represents conveying the main current of solvent **32** from flash tank outlet **208** of third flash tank **94** to upper liquid inlet **64** of main absorber **14**. The configuration and arrangement of the various components of absorption system **10d**, as shown in FIG. **6**, illustrates operating third flash tank **94** at subatmospheric pressure, operating second flash tank **84** at a second flash pressure that is greater than the subatmospheric pressure of third flash tank **94**, and operating first flash tank **76** at a first flash pressure that is greater than the second flash pressure of second flash tank **84**. Arrow **236** represents injecting stripper gas **202** into third flash tank **94** at an injection point that is downstream of flash tank inlet **206** and upstream of the flash tank outlet **208**. Arrow **238** represents stripper gas **202** collecting impurities from solvent **32** flowing through third flash tank **94**, thereby creating impure stripper gas **204**. And compressor **96** represents sucking impure stripper gas **204** at subatmospheric pressure out from within third flash tank **94**.

In the example shown in FIG. **7**, absorption system **10e** is a combination of system **10c** (FIG. **5**) and system **10d** (FIG. **6**). Specifically, with system **10e** of FIG. **7**, solvent **32** is cleaned via stripper gas **202** (FIG. **6**) and cleaned via absorbers **130** and **132** (FIGS. **1** and **5**).

Additional points worth noting are as follows. Each of the various absorbers mentioned herein (e.g., main absorber, ancillary absorber, polishing absorber) do not necessarily have to be a single vessel but, in some examples, can actually be a group or set of absorber vessels. For instance, in some examples, a main absorber comprises two or more main absorber vessels connected in series or parallel flow relationship with each other. In examples where two absorbers are incorporated within a single vessel, e.g., absorbers **14'** and **132'** of FIG. **4**, a transition area (e.g., area **162**) can serve as both a fluid inlet for one absorber and a fluid outlet for the other absorber. For example, area **162** serves as a gas inlet for polishing absorber **132'** and a gas outlet for main absorber **14'**. Likewise, area **162** serves as a solvent inlet for main absorber

12

**14'** and a solvent outlet for polishing absorber **132'**. The term, "main solvent loop" means the fluid path along which the solvent circulates through a main absorber and a flash system. The terms, "after" and "following" refer to a flow stream's molecules' experience and not the overall stream's experience. For example, a stream of solvent might flow continuously through two vessels connected in series flow relationship; however, individual molecules in the solvent stream flow through the vessels sequentially, i.e., the molecules flow through one vessel "after" the other, or the molecules flow through a downstream vessel "following" their flowing through an upstream vessel.

Although certain example methods, apparatus and articles of manufacture have been described herein, the scope of the coverage of this patent is not limited thereto. On the contrary, this patent covers all methods, apparatus and articles of manufacture fairly falling within the scope of the appended claims either literally or under the doctrine of equivalents.

The invention claimed is:

1. A method for using a solvent in treating a gas from a landfill, wherein the gas and the solvent have a varying concentration of carbon dioxide, the method comprising:
  - circulating a main current of solvent in a main solvent loop that passes through a main absorber and a flash system such that the main current of solvent flows through the main absorber and through the flash system;
  - diverting a portion of solvent from the main solvent loop to create an offshoot solvent path conveying an ancillary current of solvent and a polishing current of solvent, the ancillary current of solvent flowing through an ancillary absorber, the polishing current of solvent flowing through a polishing absorber;
  - conveying a current of nitrogen through the ancillary absorber, thereby exposing the ancillary current of solvent to the current of nitrogen;
  - conveying the gas through the main absorber, thereby exposing the gas to the main current of solvent;
  - following conveying the gas through the main absorber, conveying the gas through the polishing absorber, thereby exposing the gas to the polishing current of solvent;
  - after exposing the gas to the polishing current of solvent, injecting the portion of solvent back into the main solvent loop;
  - the main current of solvent extracting carbon dioxide from the gas flowing through the main absorber;
  - the polishing current of solvent extracting carbon dioxide from the gas flowing through the polishing absorber;
  - the flash system releasing carbon dioxide from the main current of solvent flowing through the flash system; and
  - the current of nitrogen extracting carbon dioxide from the ancillary current of solvent flowing through the ancillary absorber.

\* \* \* \* \*